

**Search Notes**

Application No.

10/605,326

Examiner

Stephen W. Smoot

Applicant(s)

YEH ET AL.

Art Unit

2813

**SEARCHED**

Class	Subclass	Date	Examiner
438	525	8/21/2004	SWS
438	528	8/21/2004	SWS
438	586	8/21/2004	SWS
438	592	8/21/2004	SWS
438	595	8/21/2004	SWS
438	637	8/21/2004	SWS
438	675	8/21/2004	SWS
438	766	8/21/2004	SWS
438	770	8/21/2004	SWS
Updated	Above	2/2/2005	SWS
Updated	Above	4/6/2005	SWS

S.W.S.  
S.W.S.  
S.W.S.

**INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner
Same as Above		4/6/2005	SWS

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
Key Words: Ion Implantation - Tilt, Sidewall; Thermal Oxidation; Rapid Thermal Process;	8/21/2004	S.W.S. SWS
Self-Aligned Contact (SAC); Plug; Contact Opening, Contact Hole, Conductive Via; Gate, Source, Drain.	8/21/2004	S.W.S. SWS
Updated Above Search	2/2/2005	S.W.S. SWS
Implantation - Nitrogen, Oxygen, Argon; Field Effect Transistors.	2/2/2005	S.W.S. SWS
Updated Above Searches	4/6/2005	S.W.S. SWS
Search Tools - EAST (attached): USPAT; US PG PUBS; Derwent; EPO; JPO; IBM TDB	8/21/2004; 2-2-05; 4-6-05	SWS S.W.S.